

Title (en)

Method of manufacturing an anode for x-ray tubes

Title (de)

Verfahren zur herstellung einer Anode für Röntgenröhren

Title (fr)

Procédé de fabrication d'une anode pour tubes à rayons x

Publication

EP 0874385 A1 19981028 (DE)

Application

EP 98201236 A 19980417

Priority

AT 24497 U 19970422

Abstract (en)

The anode manufacture has a base body provided with a coating for emission of different X-ray radiations via an inductive plasma spray coating process. The coating may be built up from a number of thin coating layers with an overall thickness of between 0.4 and 0.6 mm. A recess may be formed in the surface of the base body with a depth corresponding to the coating thickness, before application of the coating in the base of the recess, so that the surface of the applied coating is flush with the surface of the remainder of the base body.

Abstract (de)

Die Erfindung betrifft ein Verfahren zur Herstellung einer Anode für Röntgenröhren. Erfindungsgemäß wird der Röntgenstrahlung emittierende Belag durch induktives Plasmaspritzen auf dem Grundkörper aufgebracht. Dadurch wird eine verbesserte Ermüdungsrißfestigkeit und damit eine geringere Aufrauung des Belages erreicht (Fig. 2). <IMAGE>

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H01J 35/10; **H01J 9/14**

IPC 8 full level

H01J 9/14 (2006.01); **H01J 35/10** (2006.01)

CPC (source: EP US)

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Citation (search report)

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